

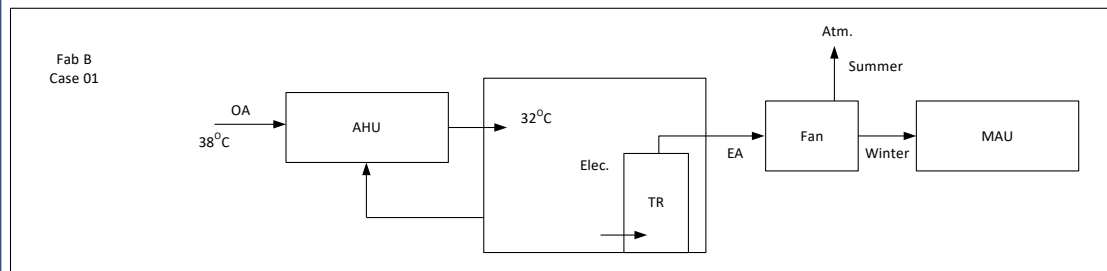


- **Education:** PhD, Department of Architectural Engineering, Liverpool University
- **Expertise:** Clean Room Design, Indoor Air Quality Control, Air Conditioning System Design, Semiconductor Optoelectronics and Factory Systems, Fluid Mechanics, Heat Transfer
- **RCEC Principal Research:** Clean room and high-tech factory facilities technology
- **RCEC Research Goals:** 1. Use heat recovery technology, optimization of operating parameters and automatic adjustment of energy-saving modes to improve the energy efficiency of clean room air conditioning systems. 2. The preheating energy consumption of the air conditioning system is reduced by more than 10%.

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Can save 13.8% of energy consumption of heating system

Research on energy saving of the heating system of the outdoor air conditioning box by recycling the waste heat of the electric power machine room

Energy consumption analysis and energy saving research of high-tech factories

Air Cond. System

System parameters table:

項目	單位	數值	備註
室內溫度	℃	26.0	
室外溫度	℃	32.0	
濕度	%	50	
風速	m/s	2.0	
風向	°	180	

Cooling Loads

編號	房間名稱	房間面積	人員數	設備數	冷負荷
1	1F-101	127.00	10	1	10.00
2	1F-102	127.00	10	1	10.00
3	1F-103	127.00	10	1	10.00
4	1F-104	127.00	10	1	10.00
5	1F-105	127.00	10	1	10.00
6	1F-106	127.00	10	1	10.00
7	1F-107	127.00	10	1	10.00
8	1F-108	127.00	10	1	10.00

Process Tool

Process flow diagram showing various equipment and flow rates.

Chiller System

編號	房間名稱	房間面積	人員數	設備數	冷負荷
1	1F-101	127.00	10	1	10.00
2	1F-102	127.00	10	1	10.00
3	1F-103	127.00	10	1	10.00
4	1F-104	127.00	10	1	10.00
5	1F-105	127.00	10	1	10.00
6	1F-106	127.00	10	1	10.00
7	1F-107	127.00	10	1	10.00
8	1F-108	127.00	10	1	10.00

Fans

編號	房間名稱	房間面積	人員數	設備數	冷負荷
1	1F-101	127.00	10	1	10.00
2	1F-102	127.00	10	1	10.00
3	1F-103	127.00	10	1	10.00
4	1F-104	127.00	10	1	10.00
5	1F-105	127.00	10	1	10.00
6	1F-106	127.00	10	1	10.00
7	1F-107	127.00	10	1	10.00
8	1F-108	127.00	10	1	10.00

Pumps

編號	房間名稱	房間面積	人員數	設備數	冷負荷
1	1F-101	127.00	10	1	10.00
2	1F-102	127.00	10	1	10.00
3	1F-103	127.00	10	1	10.00
4	1F-104	127.00	10	1	10.00
5	1F-105	127.00	10	1	10.00
6	1F-106	127.00	10	1	10.00
7	1F-107	127.00	10	1	10.00
8	1F-108	127.00	10	1	10.00

Operating Condition

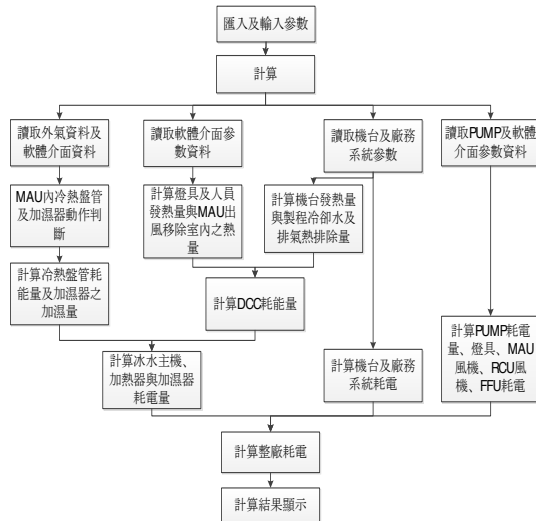
編號	房間名稱	房間面積	人員數	設備數	冷負荷
1	1F-101	127.00	10	1	10.00
2	1F-102	127.00	10	1	10.00
3	1F-103	127.00	10	1	10.00
4	1F-104	127.00	10	1	10.00
5	1F-105	127.00	10	1	10.00
6	1F-106	127.00	10	1	10.00
7	1F-107	127.00	10	1	10.00
8	1F-108	127.00	10	1	10.00

Energy Conversion Factor

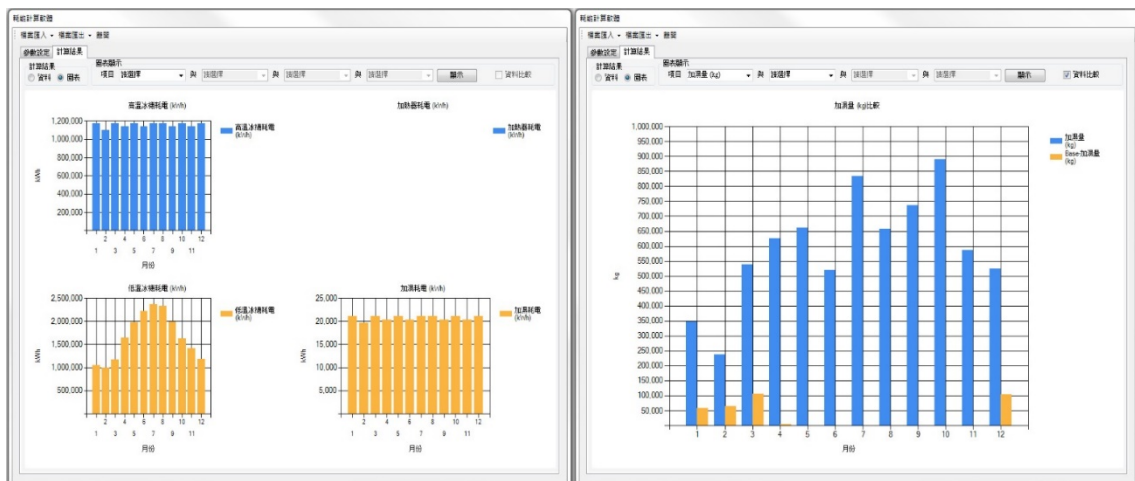
Item	ECF value	Unit	Operating conditions
Low Temperature Chiller	0.1932	(kW/kW)	Used in cooling coils of MAU
High Temperature Chiller	0.1597	(kW/kW)	Used in cooling coils of Dry Coils and PCW
high temperature heater	0.0313	(kW/kW)	Used for preheating and reheating coil in MAU
Compressed dry air	0.1181	(kW/hm³)	Supply pressure: 6.5 kg/cm² (about 6.5*10⁵ Pa)
FFU	0.1361	(kW/kW)	Class 10 Flow rate: 10,784.534 m³/h
	0.1704	(kW/kW)	Class 100 Flow rate: 9,108.418 m³/h
	0.1399	(kW/kW)	Class 1,000 Flow rate: 4,629.442 m³/h
	0.0097	(kW/kW)	Class 10,000 Flow rate: 238,049 m³/h
Make-up air	0.1127	(kW/hm³)	Flow rate: 1,256,053 m³/h
PCW	0.9440	(kW/hm³)	Water cooled by refrigeration process. Supply Pressure: 5 kg/cm² (about 5*10⁵ Pa)
General exhaust air	0.0010	(kW/hm³)	Flow rate: 455,640 m³/h
Alkaline exhaust air	0.0007	(kW/hm³)	Flow rate: 208,070 m³/h
Acid exhaust air	0.0010	(kW/hm³)	Flow rate: 150,505 m³/h
Flammability exhaust air	0.0022	(kW/hm³)	Flow rate: 72,226 m³/h
Solvent exhaust air	0.0022	(kW/hm³)	Flow rate: 118,854 m³/h

Data Input

Energy consumption analysis and energy saving research of high-tech factories



Energy Consumption Cal.



Analysis of energy saving effectiveness

Total solution on micro contamination for wafer AMHS



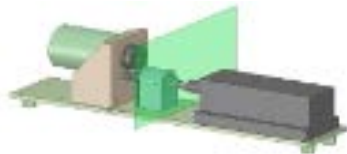
**Wafer transportation
system**



**Wafer box (FOUP)
with gas purge diffusers**



**Laminar Air Curtain
(LAC)**



**Airflow and Particle visualization
system
for large area application (L-PIV)**



**Wafer environment
monitoring sensor system
(wafer sense)**

Full-Scale Fiber & Chemical Filter Test Rigs



Fiber Filter Test Rig

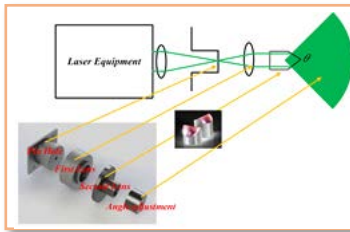


Loading Capacity testing system for EPA/ULPA

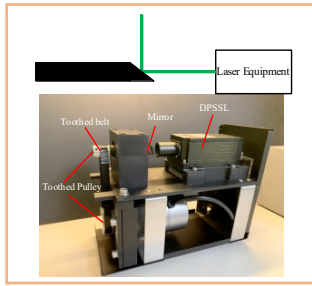


Full Scale Chemical Filter Test Rig.

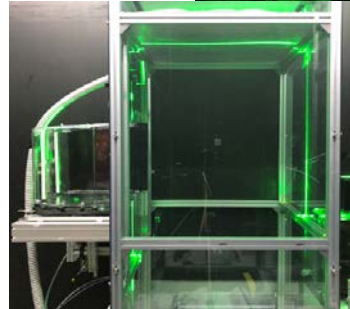
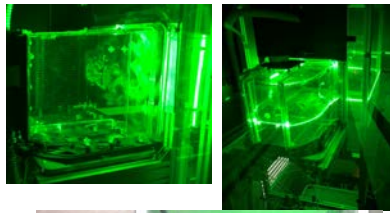
Large Scale Particle Image Velocimetry (L-PIV)



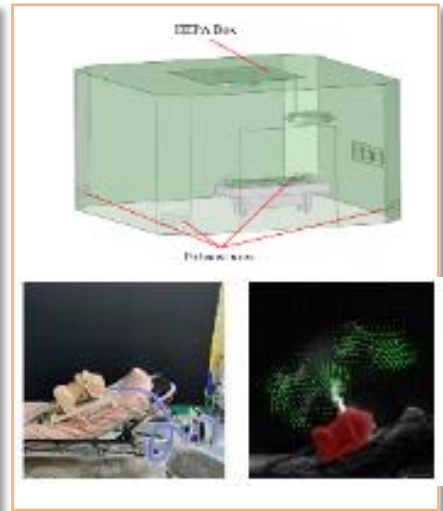
Gaussian Laser Beam



L-PIV system



Flow Visualization on FOUP
by L-PIV



Flow Visualization on
hospital operation theater
and lung intubation by
L-PIV